| L Number | Hits | Search Text | DB | Tim stamp |
|---|---|---|---|---|
| 21 | 116 | (acc leration near s ns r) and 257/415 | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/12 09:40 |
| 22 | 28 | (acceleration near sensor).clm. and 257/415 | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/12 09:40 |
| - | 21157 | acceleration adj sensor | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:12 |
| - | 2028 | (acceleration adj sensor).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:12 |
| - | 177 | (acceleration adj sensor).clm. and beam.clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:12 |
| - | 5 | (acceleration adj sensor).clm. and beam.clm. and (piezoresistor).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:13 |
| - | 0 | (acceleration adj sensor).clm. and beam.clm. and (piezoresistor).clm. and (tft or (thin near film near transistor)).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:13 |
| - | 0 | (acceleration adj sensor).clm. and (piezoresistor).clm. and (tft or (thin near film near transistor)).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:13 |
| - | 0 | (acceleration adj sensor).clm. and (tft or (thin near film near transistor)).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:16 |
| - | 1 | (acceleration adj sensor).clm. and (tft or (thin near film near transistor)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:17 |

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| - | 26 | (ac l rati n adj sensor) and (tft or (thin n ar film near transist r)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:17 |
| - | 3 | (acceleration adj sensor) and (tft or (thin near film near transistor)) and (piezo or piezoresistor) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:17 |
| - | 165494 | sensor.clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:17 |
| - | 259 | sensor.clm. and (tft or (thin near film near transistor)).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:18 |
| - | 0 | sensor.clm. and (tft or (thin near film near transistor)).clm. and piezoresistor.clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:19 |
| - | 0 | (acceleration near sensor).clm. and (tft or (thin near film near transistor)).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:20 |
| - | 6870 | (tft or (thin near film near transistor)).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:20 |
| - | 259 | (tft or (thin near film near transistor)).clm. and sensor.clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:21 |
| - | 26 | (tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:21 |
| - | 15 | (tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. and sensor.ab. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:22 |

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| - | 9 | (tft or (thin n ar film n ar transist r)).clm. and sens r.clm. and beam.clm. and s ns r.ab. and substrat .clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:22 |
| - | 9 | (tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. and sensor.ab. and substrate.clm. and (tft or (thin near film near transistor)).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:22 |
| - | 0 | (tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. and sensor.ab. and substrate.clm. and (tft or (thin near film near transistor)).ab. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:22 |
| - | 0 | (tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. and sensor.ab. and substrate.clm. and (piezo or piezoelectric or piezoresistor) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:23 |
| - | 0 | (tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. and sensor.ab. and substrate.clm. and (piezo or piezoelectric or piezoresistor).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:23 |
| - | 1 | (tft or (thin near film near transistor)).clm. and sensor.clm. and sensor.ab. and substrate.clm. and (piezo or piezoelectric or piezoresistor).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:23 |
| - | 2099 | (acceleration near sensor).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:24 |
| - | 0 | (acceleration near sensor).clm. and (tft or (thin near film near transistor)).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:24 |
| - | 1 | (acceleration near sensor).clm. and (tft or (thin near film near transistor)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:24 |
| - | 201 | (acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:24 |

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| - | 201 | (acc leration n ar s ns r).clm. and (piez or piez electric r piezoresistor).clm. | USPAT; U -PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:27 |
| - | 31 | (acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:28 |
| - | 4 | (acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and (thin near film) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:28 |
| - | 4 | (acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and ((thin near film) or tft) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:28 |
| - | 1 | (acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and ((thin near film) or tft).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:29 |
| - | 0 | (acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and (tft).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:29 |
| - | 0 | (acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and (tft) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:29 |
| - | 4 | (sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and (tft) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:32 |
| - | 2099 | (acceleration near sensor).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:32 |
| - | 56 | (acceleration near sensor).clm. and (insulating or dielectric).clm. and substrate.clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:33 |

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| - | 0 | (accelerati n near sensor).clm. and (insulating or dielectric).clm. and substrate.clm. and tft | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:33 |
| - | 23 | (acceleration near sensor).clm. and (insulating or dielectric).clm. and substrate.clm. and (tft or (thin near film)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:33 |
| - | 0 | (acceleration near sensor).clm. and (insulating or dielectric).clm. and substrate.clm. and (tft or (thin near film near transistor)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:34 |
| - | 4380 | (insulating or dielectric).clm. and substrate.clm. and (cantilever or beam).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:35 |
| - | 3 | (insulating or dielectric).clm. and substrate.clm. and (cantilever or beam).clm. and piezoresistor.clm.\ | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:35 |
| - | 3 | (insulating or dielectric).clm. and substrate.clm. and (cantilever or beam).clm. and piezoresistor.clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:35 |
| - | 0 | (insulating or dielectric).clm. and substrate.clm. and (cantilever or beam).clm. and piezoresistor.clm. and (acceleration near sensor).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:35 |
| - | 0 | (insulating or dielectric).clm. and substrate.clm. and (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:36 |
| - | 31 | (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:36 |
| - | 21 | (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:39 |

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| - | 13 | (cantilev r r beam).clm. and (piezo r piezoel ctric r pi zoresistor).clm. and (acceleration near sens r).clm. and (acceleration near sensor).ab. and beam.clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:39 |
| - | 6 | (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:40 |
| - | 0 | (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (insulating or dielectric).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:40 |
| - | 1 | (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (thin near film).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:42 |
| - | 0 | (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (thin near film).clm. and (pcb or printed).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:42 |
| - | 0 | (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (pcb or printed).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:42 |
| - | 6 | (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:42 |
| - | 4 | (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (cantilever or cantilevered).clm. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:43 |
| - | 4 | (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (cantilever or cantilevered).clm. and (cantil v r r cantilever d).ab. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/06 11:45 |